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PATENT

Attorney Docket No. 8003-370

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application)
Inventor(s): Park et al.)
Application Serial No.: 09/624,712)
Filed: July 25, 2000)
Title: Method For An Improved Developing Process)
In Wafer Photolithography)

PATENT APPLICATION

Art Unit: 1756

Examiner: K. Duda

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AMENDMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Introductory Comments:

Applicants submit this Amendment in response to the Final Office Action dated December 10, 2002. A request for continued examination (RCE) of the present application is submitted herewith and reconsideration is respectfully requested in view of the following amendments and remarks.

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